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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 1 of 4 sheets

Complete if Known

Application Number	10/029,373
Filing Date	12/20/2001
First Named Inventor	Chung J. Lee
Group Art Unit	
Examiner Name	
Attorney Docket Number	108324.00007 DIEL-0006

U.S. PATENT DOCUMENTS

Examiner Initials *	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number - Kind Code ² (if known)			
<i>gml</i>	1	SN 09/925,712	08/09/2001	Lee	Entire Content
<i>gml</i>	2	US 3,268,599	08/23/1966	Chow	Entire Content
<i>gml</i>	3	US 3,274,267	09/20/1966	Chow	Entire Content
<i>gml</i>	4	US 3,280,202	10/18/1966	Gilch	Entire Content
<i>gml</i>	5	US 3,288,728	11/29/1966	Gorham	Entire Content
<i>gml</i>	6	US 3,332,891	07/25/1967	Chow et al.	Entire Content
<i>gml</i>	7	US 3,342,754	09/19/1997	Gorham, et al.	Entire Content
<i>gml</i>	8	US 3,349,045	10/24/1967	Gilch	Entire Content
<i>gml</i>	9	US 3,379,803	04/23/1968	Tittmann, et al.	Entire Content
<i>gml</i>	10	US 3,503,903	03/31/1970	Shaw, et al.	Entire Content
<i>gml</i>	11	US 3,509,075	04/28/1970	Niegish et al.	Entire Content
<i>gml</i>	12	US 3,626,032	12/07/1971	Norris	Entire Content
<i>gml</i>	13	US 3,694,495	09/26/1972	Norris	Entire Content
<i>gml</i>	14	US 3,940,530	02/24/1976	Loeb et al.	Entire Content
<i>gml</i>	15	US 5,268,202	12/07/1993	You, et al.	Entire Content
<i>gml</i>	16	US 5,538,758	07/23/1996	Beach, et al.	Entire Content
<i>gml</i>	17	US 5,879,808	03/09/1999	Wary, et al.	Entire Content
<i>gml</i>	18	US 5,958,510	09/28/1999	Sivaramakrishnam,	Entire Content
<i>gml</i>	19	US 6,130,171	10/10/2000	Gomi	Entire Content
<i>gml</i>	20	US 6,140,456	10/31/2000	Foggiator	Entire Content
<i>gml</i>	21	US 6,265,320	07/24/2001	Shi, et al.	Entire Content

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Examiner Initials *	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ - Number ⁴ - Kind Code ⁵ (if known)				
<i>gml</i>	22	EP 0 349 032 A2	01/03/1990	Van der Werff,	/	
<i>gml</i>	23	EP 0 523 479 A2	01/20/1993	Lawrence, et al.		
<i>gml</i>	24	EP 0 856 503 A1	08/05/1998	Maruyama, et al.		
<i>gml</i>	25	GB 650 947	03/07/1951	Szwarc		

Examiner Signature

Mark Patton

Date Considered

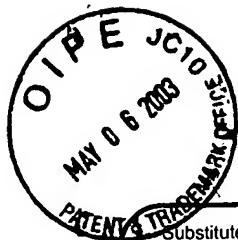
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OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS

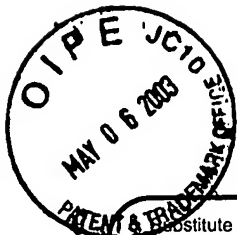
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<i>M.P.</i>	34	BRUN A.E. 100NM: THE UNDISCOVERED COUNTRY, SEMICONDUCTOR INTERNATIONAL, P79, FEB. 2000	
<i>M.P.</i>	35	CHOW, S. W., et al., "The synthesis of 1,1,2,2,9,9,10,10-octafluorou2, 2Paracyclophane" Journal of Organic Chemistry, American Chemical Society. Easton, US Vol 35(1), 1970 pages 20-22.	
<i>M.P.</i>	36	CHOW, S. W., et al., "Poly (a,a,a',a'-tetrafluoro-p-xylylene)," Journal of Applied Polymer Science, New York, NY< US, Vol. 13, No. 9, 1969, pgs. 2325-2332.	
<i>M.P.</i>	37	YANG, G.-R. et al., "High Deposition Rate Parylene Films," Journal of Crystal Growth, North-Holland Publishing Co., Amsterdam, NL, Vol. 183, No. 3, 1998, pgs. 385-390	
<i>M.P.</i>	38	GREINER, A, "Poly(1,4-xylylene)s: Polymer Films by Chemical Vapour Deposition," Trends in Polymer Science, Elsevier Science Publishers B. V. Amsterdam, NL, Vol. 5, No. 1, 1997, pgs. 12-16	
<i>M.P.</i>	39	HARRUS, A. S., et al., "Parylene Af-4: A Low ϵ_r Material Candidate for ULSI Multilevel Interconnect Applications," Material Research Society Symposium Proceedings, Vol. 443, 1997	
<i>M.P.</i>	40	IWAMOTO, R., et al., "Crystal Structure of Poly-p-xylylene. I. The a Form," Jour. Polymer. Sci. Polymer. Phys. Ed., Vol. 11, (1973), pgs. 2403-2411.	
<i>M.P.</i>	41	IWAMOTO, R., et al., "Crystallization During Polymerization of Poly-p-xylylene. III. Crystal Structure and Molecular Orientation as a Function of Temperature," Jour. Polymer. Sci. Polymer. Phys. Ed., Vol. 13, (1975), pgs. 1925-1938.	
<i>M.P.</i>	42	LANG, C.-I, "Vapor Deposition of Very low k Polymer Films, Poly (Naphthalene), Poly (Fluorinated Naphthalene)" Materials Research Society Symposium Proceedings, Materials Research Society, Pittsburgh, PA US, Vol. 381, 17 April 1995 (1995-04-17), pgs. 45-50	
<i>M.P.</i>	43	LEE C. J. "Polyimides, polyquinolines and polyquinoxalines: Tg-Structure Relationships" Macromol. Chem. Phys. C29(4) 431-560 (1989)	
<i>M.P.</i>	44	LEE, C, "TRANSPORT POLYMERIZATION OF GASEOUS INTERMEDIATES AND POLYMER CRYSTALS GROWTH", J. MACROMOL. SCI-REV. MACROMOL. CHEM., C16 (1), 79-127 (1977-78), PP79-127)	
<i>M.P.</i>	45	MATHUR, D., et al., "Vapor Deposition of Parylene-F Using Hydrogen as Carrier Gas," Journal of Materials Research, Vol. 14, No. 1, 1999, pgs. 246-250	

Examiner Signature	<i>Marc Patterson</i>	Date Considered	<i>1/6/04</i>
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Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
M.P.	46	MORGEN, M., et al., "Morphological Transitions in Fluorinated and Non-Fluorinated Parylenes," Material Research Society Symposium Proceedings, Vol. 565, 1999, pgs. 297-302	
M.P.	47	PENG Z., AND MCGIVERN, SEAN., "QUANTUM YIELDS AND ENERGY PARTITIONING IN THE UV PHOTODISSOCIATION OF HALON 2402", JOUR. OF CHEM. PHYS. VOL 113, NO.17, P7149-7157 (2000).	
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M.P.	50	RIEDEL, W., "ELECTRO-LESS NICKEL PLATING 2 ND EDITION", ASM INTERNATIONAL, FINISHING PUBLICATION LTD. 1998	
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M.P.	53	WARY J, ET AL., POLYMER DEVELOPED TO BE INTERLAYER DIELECTRIC, SEMI-CONDUCTOR INTERNATIONAL, 211-216, JUN. 1996.	

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Signature*Marc Petten*

Date

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